Dry Scrubber

Treating exhaust gas by adsorbent adsorption, simple and convenient, especially suitable for BF3, PH3, AsH3, SiH4 etc.

<table>
<thead>
<tr>
<th>Abatement Type</th>
<th>DS-11</th>
</tr>
</thead>
<tbody>
<tr>
<td>Scrubber Type</td>
<td>Dry</td>
</tr>
<tr>
<td>Dimensions (mm)</td>
<td>850W * 850D * 1950H</td>
</tr>
<tr>
<td>Weight</td>
<td>615Kg</td>
</tr>
<tr>
<td>Total Flow rate</td>
<td>200LPM</td>
</tr>
<tr>
<td>Temperature (For Processing Gas)</td>
<td>Room Temp</td>
</tr>
<tr>
<td>Max. No. of Inlet ports</td>
<td>Up to 1</td>
</tr>
<tr>
<td>Inlet Port Type option</td>
<td>NW-50</td>
</tr>
<tr>
<td>Outlet Port Type</td>
<td>1 * ISO100</td>
</tr>
</tbody>
</table>
Application & DRE:

1. PFC Abatement: CF4, C2F6, C3F8, SF6, Other Per fluorinated Gases (PFC), Hydride(AsH3>99%, PH3>99%), Acid (BF3>99%, BCl3, CL2), SiH4

Process:

- Etching, Ion Implantation
- Waste gas abatement in all LP/PE CVD processes, ion implantation, and epitaxial processes. The Dry Bed Absorber offers a safe, efficient and reliable point-of-use abatement solution for the semiconductor, photovoltaic and related industries. Providing a non-revisable chemical capture.
Advantage:
• High abatement efficiency: High decomposition & removal performance.
• Transfer of contaminants from gas to solid materials.
• Built in by-pass system, avoid process interruption.
• Epochal saving operation cost.
• Treatment for soluble gases.
• Long PM Cycle.
• Easy maintenance.
• Easy operation.
• Compatible with wet scrubber.
• Approved by SEMI S2.
• Zero water consumption.
• High gas flow & high treatment capacity.
• Zero down time.
• Reduction of byproduct Gas.
Advantage:

- If you spent one broken tower, the tower can be switched with another treatment.
- Change adsorbent equipment do not stop.
- Non-toxic gases release process can handle the processing of such seal highly toxic AsH3, sealed structure can safely handle.
- The water does not require fuel gas such as SiH4, is useful if you can not handle with water.
- Without using the fuel in order, there is no emission of CO2.
- Sealing process can handle such a highly toxic AsH3.
- Non-toxic gases release process can be handled safely sealed structure.
- Gases such as SiH4, is useful if you can not handle with water.
- The majority of speciality process gases used in wafer processing, solar and MEMS manufacturing are either pyrophoric, toxic, or corrosive. Safety of personnel and protection of the environment are matters of the highest priority.
Advantage:

- The IPI-Adsorbent waste gas abatement system removes hazardous process gases on the basis of chemical conversion (chemisorption) to stable salts at ambient temperature. No external heating, moisturisation, or other facilities are required for operation. Hence the IPI-Adsorbent system is fully passive, and is permanently on stand-by, even in the event of a power- or other facilities failure.
- IPI-Adsorbent systems customers worldwide avail of a local service for the collection and refilling of expended IPI-Adsorbent columns, which are patented, and reusable transport containers.
- A wide range of IPI-Adsorbent model sizes are available to meet the needs of all our customers- from small-scale university researchers to round-the-clock wafer fabrication.
- Delivers continuous operation, 24 hours a day, 365 days a year.
- Incorporates filtration technology for removing particulate matter.
- Forced air design accelerates oxidation.
- Features a longer maintenance cycle and improved safety.
Advantage:

• IPI-Adsorbent systems is a high-end dry type waste gas abatement system featuring a variety of control functions designed to facilitate smooth manufacturing equipment operation as well as a special structure capable of continuous waste gas abatement over the long term.

• Absorption dry-type gas abatement system. This safely handles AsH3 and so on which needs hermetically-sealed treatment.

• Column 2 is also available with built-in tower 2 tower type apparatus, are also available switching devices can be used.

• Automatic switching system was also available. Sealing process can handle such a highly toxic AsH3.

• Gases such as SiH4, is useful if you can not handle with water.